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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Kazuo ICHIKAWA et al.

Group Art Unit: 1763

Application No.: 09/670,877

Examiner: R. ZERVIGON

Filed: September 27, 2000

Docket No.: 107469

For: CVD SUBSTRATE AND CLEANING METHOD

SUMMARY OF SUBSTANCE OF INTERVIEW

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Applicants appreciate the courtesies shown to Applicants' representatives by Examiner Zervigon and Examiner Hassanzadeh in the January 4, January 10 and January 11 telephone conferences.

As a result of the above telephone conferences, Applicants' representatives received a voice mail message from Examiner Zervigon informing Applicants' representatives that the Amendment After Final Rejection (AAFR) filed December 11, 2006, and the English-language translation of priority document Japanese Patent Application No. 11-274216 submitted with the December 11 AAFR, will be entered into the record, without the filing of a Request for Continued Examination (RCE).

The voice mail received from Examiner Zervigon stated that a new Office Action would be issued.

Based on the message received from Examiner Zervigon, Applicants' representatives understand that no further action is required by Applicants until the new Office Action is mailed from the U.S. Patent Office with new shortened statutory period for response.

Should any questions arise regarding this submission, all inquiries may be directed to Applicant's undersigned representative at the telephone number set forth below.

Respectfully submitted,



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JAO:JMH

Date: January 11, 2007

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